

AP20 Rec'd PCT/PTO 28 JUN 2006

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Isao YOKOKAWA

Application No.: New U.S. Patent Application

Filed: June 28, 2006

Docket No.: 128503

For: METHOD FOR MEASURING AN AMOUNT OF STRAIN OF A BONDED STRAINED
WAFERINFORMATION DISCLOSURE STATEMENTCommissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

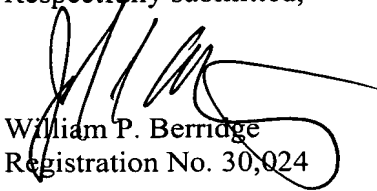
Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- ☒ 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- ☒ 2. Relevance of one or more non-English language reference is discussed in the present specification. See References 1 - 3 and 8.
- ☒ 3. One or more reference cited herein was cited in the International Search Report. A copy of the International Search Report is attached for the Examiner's information. According to the Notification of Acceptance in this file, a copy of each reference is already in the PTO file. Thus, no copy of any such reference is attached. See References 4 - 7 and 9.
- ☒ 4. An English language Abstract of one or more non-English language reference is attached hereto. See References 1 - 7.



5. A computer-generated English language translation of one or more Japanese Patent Publication cited herein has been obtained from the website of the Japanese Patent Office ([<http://www.jpo.go.jp>]), and is attached, but has not been reviewed for accuracy. See References 1 - 7.

Respectfully submitted,


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Form PTO-1449 (REV. 1/06)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 128503		APPLICATION NO. New U.S. Patent Application 104584771	
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)				APPLICANT Isao YOKOKAWA			
				FILING DATE June 28, 2006		GROUP	

U.S. PATENT DOCUMENTS						
Examiner Initials	Cite No.	Document Number	Date	Name		

FOREIGN PATENT DOCUMENTS						
Examiner Initials	Cite No.	Document Number	Date	Country	With English Abstract	With English Translation
	1	JP A 2001-217430	8/10/2001	Japan	X	X
	2	JP A 2002-164520	6/7/2002	Japan	X	X
	3	JP A 2002-305293	10/18/2002	Japan	X	X
	4	JP A 2003-229360	8/15/2003	Japan	X	X
	5	JP A 2003-229361	8/15/2003	Japan	X	X
	6	JP A 2000-286413	10/13/2000	Japan	X	X
	7	JP A 11-304729	11/5/1999	Japan	X	X

OTHER DOCUMENTS		
Examiner Initials	Cite No.	(Including Author, Title, Date, Pertinent Pages, etc.)
	8	M. Erdtmann et al, "Structural Characterization of Strained Silicon Substrates by X-Ray Diffraction and Reflectivity", Extended Abstracts of the 2003 International Conference on Solid State Devices and Material, Tokyo, pp. 290-291, 2003.
	9	W.L. Bond, "Precision Lattice Constant Determination", Acta Crystallographica, pp. 814-818, October 10, 1960.

EXAMINER	DATE CONSIDERED
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

Date: June 28, 2006